



In re application of: Van Schravendijk, et al

Application No.: 10/773,821

Filed: February 5, 2004

Title: APPLICATIONS AND METHODS OF

MAKING NITROGEN-FREE ANTI-

REFLECTIVE LAYERS FOR

SEMICONDUCTOR PROCESSING

Attorney Docket No.:

NOVLP037C1/NVLS-000519C1

Examiner: UNASSIGNED

Group: 2813

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on May 11, 2004 in an envelope addressed to the Commissioner for Patents, P.O. Box 1450

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Leslie Russell

REQUEST FOR CORRECTED FILING RECEIPT

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Sir:

Enclosed is a copy of the Filing Receipt for the above-identified patent application. Please reprint the Filing Receipt as follows and mail the corrected copy to the undersigned.

Change Applicant "M. Zlaul Karim" to -- M. Ziaul Karim --.

Since this is a Patent Office typographical error, no fee should be due. However, the Commissioner is authorized to charge any fees that may be due to Deposit Account 500388 (Order No. NOVLP037C1).

Respectfully submitted,

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FILING RECEIPT

OC000000012538268*

Date Mailed: 05/05/2004

CONFIRMATION NO. 8057

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Applicant(s)

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-- M. Ziaul Karim --

Assignment For Published Patent Application

Novellus Systems, Inc.;

Domestic Priority data as claimed by applicant

This application is a CON of 09/990,197 11/21/2001 PAT 6,720,251 which claims benefit of 60/302,112 06/28/2001

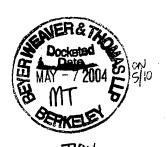
Foreign Applications

If Required, Foreign Filing License Granted: 05/05/2004

Projected Publication Date: Request for Non-Publication Acknowledged

Non-Publication Request: Yes

Early Publication Request: No



Title

Applications and methods of making nitrogen-free anti-reflective layers for semiconductor processing

Preliminary Class

438

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